

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of :  
Makoto AKIZUKI et al. :  
Serial No. NEW : **Attn: APPLICATION BRANCH**  
Filed August 27, 2003 : Attorney Docket No. 2003-1240

METHOD FOR FORMING GAS CLUSTER  
AND METHOD FOR FORMING THIN FILM  
**(Rule 1.53(b) Continuation  
of Serial No. 10/025,899,  
Filed December 26, 2001)**

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**PRELIMINARY AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In the interest of compact prosecution, please amend the present application as follows: